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CERTIFICATE OF MAILING

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Date: July 30, 2004

June Keating

Patent
36856.743

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Takahiro OGUCHI	Art Unit: 2823
Serial No.: 09/548,414	Examiner: J. A. Garcia
Filed: April 13, 2000	
Title: METHOD OF MANUFACTURING AN EXTERNAL FORCE DETECTION SENSOR	

INFORMATION DISCLOSURE STATEMENT

U.S. PATENT AND TRADEMARK OFFICE
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Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Pursuant to 37 C.F.R. § 1.56, submitted herewith are copies of seven (7) references cited in the enclosed search report issued in a corresponding European patent application.

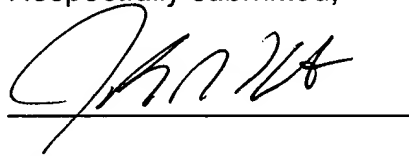
For the Examiner's convenience, we have enclosed a copy of the European Search Report and a completed Form PTO-1449. Further, although the European

Search Report cites DE 44 42 023, DE 196 10 782, DE 197 15 194, and US 5,343,064, Applicant did not include copies of the references herewith as the references have been previously cited in an Information Disclosure Statement filed on May 26, 2004. The statement is not a representation that all of the information cited is necessarily effective as prior art against the application.

I hereby state that each item of information contained in this Information Disclosure Statement was cited in a communication from a foreign patent office in a counterpart foreign application not more than 3 months prior to the filing of this statement, and that this is the first citation of these prior art references by a foreign patent office in a counterpart foreign patent application. Accordingly, no fee is necessary for the filing of this statement. Should the Commissioner determine otherwise, the Commissioner is authorized to charge Deposit Account No. 50-1353 for any fee shortages, including the petition fee under 37 C.F.R. § 1.17(p).

Applicant respectfully requests that the disclosed references be made of record in the subject application.

Respectfully submitted,



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Date: July 30, 2004

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Substitute for form 1449/PTO

Complete if Known**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(Use as many sheets as necessary)

Sheet

of

Application Number	09/548,414
Filing Date	April 13, 2000
First Named Inventor	Takahiro OGUCHI
Art Unit	2823
Examiner Name	J. GARCIA
Attorney Docket Number	36856.743

NON PATENT LITERATURE DOCUMENTS

Examiner Initials	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title Of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
	4	ZHIXIONG et al., "LATERALLY CAPACITY SENSED ACCELEROMETER FABRICATED WITH THE ANODIC BONDING AND THE HIGH ASPECT RATIO ETCHING", Solid-State and Integrated Circuit Technology 1998 Proceedings, 5 th International Conference in Beijing, China, Oct. 21-23, 1998, pp. 921-924, IEEE, Piscataway, NJ.	
	5	MOCHIDA et al, "A MICROMACHINED VIBRATING RATE GYROSCOPE WITH INDEPENDENT BEAMS FOR THE DRIVE AND DETECTION MODES", Micro Electro Mechanical Systems 1999, MEMS '99, 12 th IEEE International Conference in Orlando, FL, Jan. 17-21, 1999, pp. 618-623, IEEE, Piscataway, NJ.	
	6	KLASSEN et al., "SILICON FUSION BONDING AND DEEP REACTIVE ION ETCHING: A NEW TECHNOLOGY FOR MICROSTRUCTURES", Proc. Of Transducers '95, 8 th International Conference on Solid-State Sensors and Actuators, Stockholm, Sweden, June 25-29, 1995, pp. 556-559, Vol. 1.	
	7	FRANSSILA et al., "ETCHING THROUGH SILICON WAFER IN INDUCTIVELY COUPLED PLASMA", Microsystem Technologies, , April 2000 (2000-04), pp. 141-144, vol. 6, no. 4, Berlin, DE.	

Examiner Signature		Date Considered	
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*Examiner: Initial if reference considered, whether of not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered, include copy of this form with next communication to applicant.

¹ Applicant unique citation designation number (optional). ² Applicant is to place a check mark here if English language Translation is attached. This collection of information is required by 37 CFR 1.97 and 1.98. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14.